Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A method of forming a plurality of films on a base, the method comprising:

forming a first film of the plurality of films in a first area of the base, the forming of the first film including an ejection of a first material from a first nozzle without a solvent dissolving the first material that is carried out during a first period; and

forming a second film of the plurality of films that is formed in a second area of the base and that is separated from the first film, the forming of the second film including an ejection of the first material from the first nozzle that is carried out during a second period,

the first film being formed when the ejection of the first material from the first nozzle during the first period is completed,

the base being provided in a first chamber during the first period,

the second film being formed when the ejection of the first material from the first nozzle during the second period is completed, and

the base being provided in the first chamber during the second period.

2. (Previously Presented) The method according to Claim 1,

the base being provided in an atmosphere that is adjusted to a pressure of 10^{-3} torr or less during at least a part of the first period.

3. (Previously Presented) The method according to Claim 1,

the base being provided in an atmosphere that is adjusted to a pressure of 10^{-5} torr or less during at least a part of the first period.

4. (Previously Presented) The method according to Claim 1, further comprising:

detecting an ejection failure of the first nozzle.

5. (Previously Presented) The method according to Claim 4,

the detecting of the ejection failure of the first nozzle including an ejection of the first material from the first nozzle to a third area on the base.

6. (Previously Presented) The method according to Claim 52,

the inspection of the preliminary film being performed by a measurement of light-reflectivity of the preliminary film.

7. (Previously Presented) The method according to Claim 52,

the inspection of the preliminary film being performed by a measurement of light-transmissivity of the preliminary film.

8. (Previously Presented) The method according to Claim 1, further comprising:

forming a third film of the plurality of films that is formed on the first film, the forming of the third film including an ejection of a second material that is carried out during a third period.

9. (Previously Presented) The method according to Claim 1,

the first material being ejected in a form gas from the first nozzle to the first chamber during the first period.

10. (Previously Presented) The method according to Claim 9,

the first material being ejected in the form gas from the first nozzle to the first chamber during the second period.

11. (Previously Presented) The method according to Claim 53,

the second material being ejected in a form gas from the second nozzle to the first chamber during a third period in which the ejection of the second material from the second nozzle is carried out.

12. (Canceled).

13. (Previously Presented) The method according to Claim 8, further comprising:

forming a fourth film of the plurality of films that is formed on the second film, the forming of the fourth film including an ejection of the second material that is carried out during a fourth period.

14. (Currently Amended) A method of forming a plurality of films on a base, the method comprising:

forming a first film of the plurality of films in a first area of the base, the forming of the first film including an ejection of a first material from a first nozzle without a solvent dissolving the first material that is carried out during a first period; and

forming a second film of the plurality of films in a second area of the base, the second film being separated from the first film, the forming of the second film including an ejection of the first material from the first nozzle that is carried out during a second period,

the first film being formed when the ejection of the first material during the first period is carried out,

the base being provided in a first chamber during the first period,

the second film being formed when the ejection of the first material during the second period is completed, and

the base being provided in the first chamber during the second period.

15. (Previously Presented) A method of manufacturing an electronic device, the method comprising:

forming at least a part of the electronic device by using the method according to Claim 1.

16. (Previously Presented) The method according to Claim 15,

the first material being used for at least one of a conductive film, a semiconductor film, and an insulating film.

17. (Previously Presented) The method according to Claim 15, further comprising:

providing a pattern prior to the ejecting of the first material from the first nozzle during the first period is carried out,

the plurality of films being formed according to the pattern.

18. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:

forming at least a part of the electro-optical device by using the method according to Claim 1.

19. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising using the method of claim 1 to form:

at least a part of the electro-optical device; and

at least one of an electron-transporting layer, a hole-transporting layer, a light emitting layer, and an electrode included in an electro-optical element included in the electro-optical device.

20. (Previously Presented) The method according to Claim 19, further comprising:

forming partitions that surround at least one of the light-emitting layer, the electron-transporting layer and the hole-transporting layer.

21-30. (Canceled).

31. (Previously Presented) The method according to Claim 4,

the detecting of the ejection failure being carried out using a sensor.

32. (Previously Presented) The method according to Claim 1, further comprising:

sensing at least one film of the plurality of films.

33. (Previously Presented) The method according to Claim 32,

the sensing of the at least one film including an irradiation of the at least one film with a light source.

34. (Previously Presented) The method according to Claim 32,

the sensor measuring at least one of a transmission light that transmits the at least one film and a reflection light that is reflected by the at least one film.

35. (Previously Presented) The method according to Claim 1,

the ejection of the first material from the first nozzle during the first period is carried out at a first position of the first nozzle relative to the base, and

the ejection of the first material from the first nozzle during the second period is carried out at a second position of the first nozzle relative to the base.

36. (Previously Presented) The method according to Claim 35,

further comprising:

moving a position of the first nozzle relative to the base from the first position to the second position.

37. (Previously Presented) The method according to Claim 1,

the first nozzle being one nozzle of a plurality of nozzles provided in a discharge head.

38. (Previously Presented) The method according to Claim 1, further comprising:

sensing the first film by a sensor.

39. (Previously Presented) The method according to Claim 1, further comprising:

detecting a positional deviation between a first location on the base where the first film is actually formed and a second location on the base where the first film is to be formed.

40. (Previously Presented) The method according to Claim 18,

the electro-optical device including an organic electroluminescent element, and

the first film being one of an electron-transporting layer, a hole-transporting layer, a light-emitting layer and an electrode included in the organic electroluminescent element.

41. (Previously Presented) The method according to Claim 1,

the first nozzle being one of a plurality of nozzles,

a third material being ejected from a third nozzle of the plurality of nozzles during at least part of the first period, and

the first film including the first material and the third material.

42. (Previously Presented) The method according to Claim 1, further comprising:

performing a scanning movement of a head including the first nozzle.

43. (Previously Presented) The method according to Claim 42,

the scanning movement of the head being performed during at least a part of a fifth period between the forming of the first film and the forming of the second film.

44. (Previously Presented) The method according to Claim 42,

the first nozzle being one nozzle of a plurality of nozzles provided in the head.

45. (Previously Presented) The method according to Claim 44,

the discharge head being constructed to adjust a posture of the discharge head by a θ direction adjusting mechanism, a Z direction adjusting mechanism, and a Y adjusting mechanism.

46. (Previously Presented) The method according to Claim 45,

each of the θ direction adjusting mechanism, the Z direction adjusting mechanism, and the Y adjusting mechanism being operated.

47. (Canceled).

48. (Previously Presented) The method according to Claim 1, further comprising:

setting a first relative position of the first nozzle to the base before the forming of the first film is carried out; and

setting a second relative position of the first nozzle relative to the base before the forming of the second film is carried out.

49. (Previously Presented) The method according to Claim 1, further comprising:

setting a first relative position of the first nozzle relative to the base before the ejection of the first material from the first nozzle during the first period is carried out; and

setting a second relative position of the first nozzle, relative to the base before the ejection of the first material from the first nozzle during the second period is carried out.

50. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:

forming at least a part of the electro-optical device by the method according to Claim 41,

each of the first film and the second film being at least a part of the electro-optical device.

51. (Previously Presented) A method of manufacturing an electro-optical device, the method comprising:

forming at least part of the electro-optical device by the method according to Claim 55,

each of the first film and the second film being at least a part of the electro-optical device.

52. (Previously Presented) The method according to Claim 5,

a preliminary film being formed by the ejection of the first material from the first nozzle to the third area provided on the base, and

the ejection failure being detected based on an inspection of the preliminary film.

53. (Previously Presented) The method according to Claim 1, further comprising:

forming a third film of the plurality of films that is formed in a third area provided on the base different from the first area and that is separated from the first film, the forming of the third film including an ejection of a second material from a second nozzle different from the first nozzle.

54. (Previously Presented) The method according to Claim 1, further comprising:

forming a third film of the plurality of films that is formed on a third area of the base different from the first area, the forming of the third film including an ejection of a second material from a second nozzle different from the first nozzle that is carried out during the first period.

55. (Previously Presented) The method according to Claim 1,

a third material being ejected from the first nozzle during at least a part of the first period, and

the first film including the first material and the third material.

56. (Previously Presented) The method according to Claim 50,

an organic electroluminescent element being include in the electro-optical device, and

the first film being one of an electron-transporting layer, a hole-transporting layer, a light-emitting layer and an electrode include in the organic electroluminescent element.

57. (Previously Presented) The method according to Claim 51,

an organic electroluminescent element being include in the electro-optical device, and

the first film being one of an electron-transporting layer, a hole-transporting layer, a light-emitting layer and a an electrode include in the organic electroluminescent element.